

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Confirmation No.: 5877

Kenichi MORIMOTO

Art Unit: 1763

S. N. 10/737,393

Examiner: Allan W. Olsen

Filed: December 16, 2003

For: MASK BLANK FOR CHARGED PARTICLE BEAM EXPOSURE, METHOD OF
FORMING MASK BLANK AND MASK FOR CHARGED PARTICLE BEAM EXPOSURE

RESPONSE TO OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the office action dated July 16, 2007, for which a two month extension of time is requested to extend the period for response to Monday, December 17, 2007, please make the following amendments:

Claim amendments begin on page 2 of this document.

Remarks begin on page 4 of this document.